

METHODS AND DEVICES FOR ADJUSTING AN ELECTRON-BEAM USED
IN AN ELECTRON BEAM PROXIMITY EXPOSURE APPARATUS

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ABSTRACT OF THE DISCLOSURE

10 The present invention relates methods and devices
for adjusting an electron beam used in an electron-beam
of the electron-beam proximity exposure apparatus,
wherein the method of present invention comprising the
step of: forming the electron-beam by passing through a
aperture which has a predetermined length part, into a
15 measurement beam which has a cross section having a
measurement part thereof corresponding to the
predetermined length part of the aperture, memorizing the
calibrating information including the electron-beam,
wherein the measured lengths are the length of the
20 measurement part of the cross section of the measurement
beam measured at a predetermined distance from the
aperture under the states of the electron-beam, and each
of the states of the electron-beam indicated by the
information indicating the state of the electron-beam is
25 memorized in relation to each of the measured lengths,
measuring the length of the measurement part of the cross
section of the measurement beam at a predetermined
distance from the aperture, and calibrating the state of
the electron-beam of the electron-beam proximity exposure
30 apparatus on the basis of the length measured in the
measuring step in accordance with the calibrating
information.